

U.S. Department of Commerce, Patent and Trademark Office (PTO Form 1449 modified)					Docket No. AMAT/5192/ISM/COR E MCVD/SB	Serial No. 09/776,329
#9 INFORMATION DISCLOSURE STATEMENT BY APPLICANT					Applicant Suetter, et al.	Confirmation No.: 9575
(Use several sheets if necessary)					Filing Date	Group
Examiner Unknown					February 2, 2001	2812
U.S. Patent Documents						
*Examiner Initial	Document Number	Issue Date	Applicant(s) Name	Class	Subclass	Filing Date If Appropriate
A1						RECEIVED JAN -2 2003 TECHNOLOGY CENTER 2800
A2						
A3						
A4						
A5						
A6						
A7						
A8						
A9						
A10						
A11						
A12						
Foreign Patent Documents						
*Examiner Initial	Document Number	Date	Country	Class	Subclass	Translation
						YES <input type="checkbox"/> NO <input type="checkbox"/>
B1						<input type="checkbox"/> <input type="checkbox"/>
B2						<input type="checkbox"/> <input type="checkbox"/>
B3						<input type="checkbox"/> <input type="checkbox"/>
OTHER ART						
*Examiner Initial	Including Author, Title, Date, Pertinent Pages, Etc.					
TMT	C1	Rossnagel, S.M., et al., "Plasma-enhanced atomic layer deposition of Ta and Ti for interconnect diffusion barriers," J. Vac. Sci. Technol. B 18(4), Jul/Aug 2000				
TMT	C2	Partial Search Report (Annex to Form PCT/ISA/206), dated October 25, 2002 for PCT/US02/02651				
	C3					
Examiner	T. M. Thomas			Date Considered 07/09/03		
*EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with your communication to applicant.						